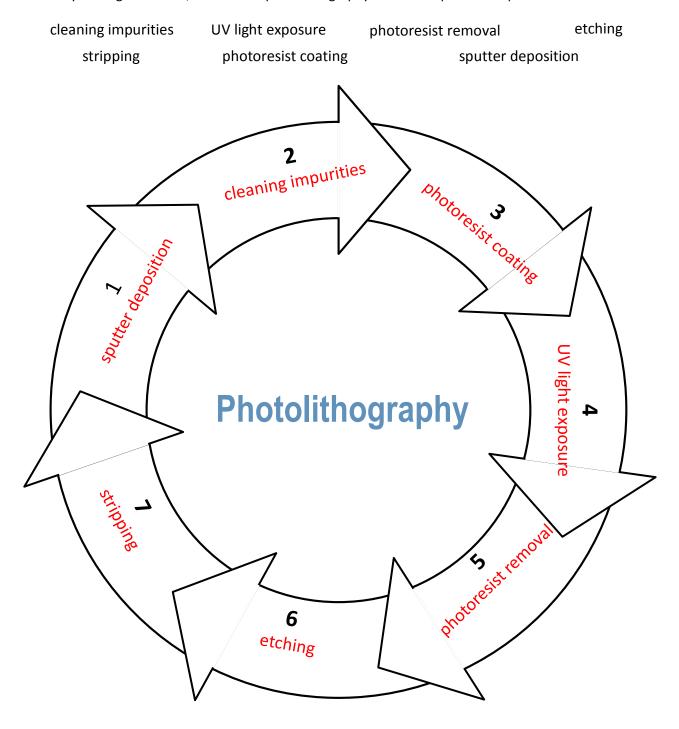
	Name:	Date:	Class:	
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## **Post-Introduction Quiz Answer Key**

## **Flexible Circuits Fabrication Cycle**

On the cycle diagram below, write in the photolithography fabrication process steps in the correct order.



Name:	Date:	Class:	

## **Terminology**

*Instructions*: Draw lines to match each photolithography step with its corresponding description.

## **Photolithography Description** Step A method of depositing thin films of a conductor material by way of eroding a "target" source onto a non-conductor "substrate." This is typically cleaning impurities accomplished by bombarding the "target" (source of deposition material) with inert gas atoms. Atoms on the "target" flies to the "substrate." A wafer coated with a thin conductor is covered with UV light-sensitive liquid by spin coating; this UV light exposure viscous liquid solution is dispensed onto a rapidly spun wafer to produce a uniformly thick layer. Organic / inorganic contaminations are usually removed by wet chemical treatment, based on solutions containing hydrogen peroxide. Other stripping solutions made with trichloro-ethylene, acetone or methanol can also be used. The photoresist that chemically reacted is removed from the substrate. This usually requires photoresist coating a liquid resist stripper or developer, which chemically alters the photoresist so that it no longer adheres to the substrate. The use of a solvent called stripper to remove the etching photoresist and any of its residues. UV light passes through a mask (a print of the circuit to be transferred to the wafer) placed on sputter deposition the conductor coated wafer. Light causes a chemical change on the photoresist over portions not covered by the mask. Using a liquid ("wet") or plasma ("dry") chemical agent, the uppermost layer of the conductor photoresist removal substrate is removed in the areas that are not protected by the photoresist